

Title (en)  
ION SOURCE WITH FOUR ELECTRODES

Publication  
**EP 0295743 B1 19920506 (FR)**

Application  
**EP 88201173 A 19880608**

Priority  
FR 8708196 A 19870612

Abstract (en)  
[origin: EP0295743A1] Vacuum arc ion-source comprising an anode (2 or 3) and a cathode (1) which are arranged facing one another, and are brought to different potentials, and in which the plasma (7) is emitted perpendicularly to the surface of the cathode. This plasma is projected by means of two suitably polarised free-standing gates (4 and 5). <??>Application to the implanting of metal ions. <IMAGE> <IMAGE>

IPC 1-7  
**H01J 27/02**; **H01J 27/08**; **H01J 49/12**

IPC 8 full level  
**H01J 27/02** (2006.01); **H01J 27/08** (2006.01); **H01J 37/08** (2006.01)

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